

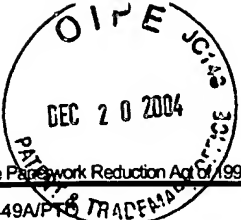
The patents and/or publications submitted herewith are set forth on the attached Form PTO-1449.

If the sum of \$180.00 is due under 37 CFR § 1.17(p) pursuant to § 1.97, the Commissioner is hereby authorized to charge this fee, and any other fee necessary to make this submission timely, to the Deposit Account No.20-0782/AMAT/7681/BKH.

Respectfully submitted,

A handwritten signature in black ink, appearing to read "B k Hrna", is written over a horizontal line.

Brian K. Hrna
Registration No. 41,852
MOSER, PATTERSON & SHERIDAN, L.L.P.
3040 Post Oak Blvd. Suite 1500
Houston, TX 77056
Telephone: (713) 623-4844
Facsimile: (713) 623-4846
Attorney for Applicant(s)



Substitute for form 1449A/PTO

**SUPPLEMENTAL
INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Sheet 1 of 3

Complete if Known

Application Number	10/803,867
Filing Date	March 18, 2004
First Named Inventor	Brooks, et al.
Art Unit	1756
Examiner Name	Unknown
Attorney Docket Number	AMAT/7681/MASK/MASK-TECH/ARNOLD S

U.S. PATENT DOCUMENTS

Examiner Initials *	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number - Kind Code ² (if known)			
	A1	US-6,709,901	03/23/2004	Yamazaki et al.	
	A2	US-6,635,185	10/21/2003	Demmin et al.	
	A3	US-6,391,791	05/21/2002	Sasaki et al.	
	A4	US-6,307,265	03/14/2000	Mui et al.	
	A5	US-6,251,217	06/26/2001	Ye et al.	
	A6	US-6,214,637	04/10/2001	Kim et al.	
	A7	US-6,114,250	09/05/2000	Ellingboe et al.	
	A8	US-6,080,529	06/27/2000	Ye et al.	
	A9	US-6,033,979	03/07/2000	Endo	
	A10	US-6,007,732	12/28/1999	Hashimoto et al.	
	A11	US-5,994,235	11/30/1999	O'Donnell	
	A12	US-5,948,570	09/07/1999	Kornblit et al.	
	A13	US-5,861,233	01/19/1999	Sekine et al.	
	A14	US-5,773,199	06/30/1998	Linliu et al.	
	A15	US-5,750,290	05/12/1998	Yasuzato et al.	
	A16	US-5,538,816	07/23/1996	Hashimoto et al.	
	A17	US-4,600,686	07/15/1986	Meyer et al.	
	A18	US-4,504,574	03/12/1985	Meyer et al.	
	A19	US-4,406,733	09/27/1983	Tachi et al.	
	A20	US-4,350,563	09/21/1982	Takada et al.	

FOREIGN PATENT DOCUMENTS

Examiner Initials *	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	† ⁶
		Country Code ³ - Number ⁴ - Kind Code ⁵ (if known)				
	B1	DE 27 01 458	01/14/1977	Sato et al.		
	B2	EP 0 978 870	02/09/2000	Sasaki et al.		
	B3	EP 0 999 472	05/10/2000	Sasaki et al.		
	B4	JP 11-131263 (English abstract)	05/18/1999	Shusaku		X
	B5	JP 2001-33940 (English abstract)	06/10/2003	Yong-Hoon		X
	B6	JP 60 016422 (English abstract)	01/28/1985	Hidefumi et al.		X
	B7	JP 60 219748 (English abstract)	11/02/1985	Kazuhiro et al.		X
	B8	JP 62 181433 (English abstract)	08/08/1987	Kazuhiro et al.		X
	B9	WO 00/67281	11/09/2000	Pong		

Examiner
SignatureDate
Considered

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ¹ Applicant's unique citation designation number (optional). ² See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.

This collection of information is required by 37 CFR 1.97 and 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.

Substitute for form 1449A/PTO

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Sheet	2	of	3
-------	---	----	---

Complete if Known

<i>Application Number</i>	10/803,867
<i>Filing Date</i>	March 18, 2004
<i>First Named Inventor</i>	Brooks, et al.
<i>Art Unit</i>	1756
<i>Examiner Name</i>	Unknown
<i>Attorney Docket Number</i>	AMAT7681/MASK/MASK-TECH/ARNOLD S

U.S. PATENT DOCUMENTS

[illegible]

FOREIGN PATENT DOCUMENTS

[illegible]

Examiner Signature		Date Considered	
-----------------------	--	--------------------	--

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ¹ Applicant's unique citation designation number (optional). ² See Kinds codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.

This collection of information is required by 37 CFR 1.97 and 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number

Substitute for form 1449B/PTO

**SUPPLEMENTAL
INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Complete if Known

Application Number	10/803,867
Filing Date	March 18, 2004
First Named Inventor	Brooks, et al.
Art Unit	1756
Examiner Name	Unknown
Attorney Docket Number	AMAT/7681/MASK/MASK-TECH/ARNOLD S

Sheet 3 of 3

NON PATENT LITERATURE DOCUMENTS

Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	C1	PCT International Search Report from International Application No. PCT/US02/27869, Dated 23 December 2002. (AMAT/6399PCT).	
	C2	PCT Search Report for PCT/US03/11549, dated February 19, 2004 (AMAT/6991.PCT).	
	C3	KWON, ET AL., "Loading Effect Parameters at Dry Etcher System and Their Analysis at Mask-to-Mask Loading and Within-Mask Loading" Proceedings of SPIE, Vol. 4562 (2002) pp. 79-87.	
	C4	FUJISAWA, ET AL. "Evaluation of NLD Mask Dry Etching System" SPIE Symposium on Photomask and X-Ray Technology VI, Yokohama, JAPAN, September (1999) Vol. 3748 pp. 147-152.	
	C5	RUHL, ET AL. "Chrome Dry Etch Process Characterization Using Surface Nano Profiling" Proceedings of SPIE, Vol. 4186 (2001) pp. 97-107.	
	C6	AOYAMA, ET AL. "Advanced Cr Dry Etching Process" SPIE Symposium on Photomask and X-Ray Technology VI, Yokohama, JAPAN, September (1999) SPIE, Vol. 3748 pp. 137-146.	

Examiner Signature		Date Considered	
-----------------------	--	--------------------	--

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Applicant's unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.

This collection of information is required by 37 CFR 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 120 minutes to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.